



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/388,826
Filing Date September 1, 1999
Inventor Weimin (Michael) Li et al.
Assignee Micron Technology, Inc.
Group Art Unit 2813
Examiner E. Kielin
Attorney's Docket No. MI22-1208
Title: Low k Interlevel Dielectric Layer Fabrication Methods

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References –See Attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the references which are listed on the attached Form PTO-1449, copies of which are attached. No admission is made regarding whether all the submitted references are prior art.

Citation of the referenced art is respectfully requested.

Respectfully submitted,

Dated: 16 Sep 2003

By: 

James E. Lake
Reg. No. 44,854

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1208	SERIAL NO. 09/388,826	
<div style="position: relative; height: 100px;"> <div style="position: absolute; top: 0; left: 0; width: 100%; height: 100%; border: 2px solid black; border-radius: 50%; text-align: center; line-height: 100px; font-size: 24px; font-weight: bold;"> OIPE SEP 16 2003 PATENT & TRADEMARK OFFICE </div> </div>				LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)		
				APPLICANT Weimin Li, et al.		
				FILING DATE September 1, 1999	GROUP 2813	
U.S. PATENT DOCUMENTS						
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
AA	6518122	02/2003	Chan et al			
AB	6492688	12/2002	Ilg			
AC	6373114	04/2002	Jeng et al			
AD	2001/0019868	09/2001	Gonzalez et al			
AE	2001/0003064	06/2001	Ohto			
AF	2003/0013311	01/2003	Chang et al			
AG						
AH						
AI						
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AM						
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)						
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